

[APPLICATION] Biaxially-textured film **deposition** for superconductor coated tapes

US Pat. 10821010 - Filed Apr 8, 2004

In this invention, the **ion beam incident angle** is arranged so that it is along the BITD while, at the same time, the **deposition flux incident plane** is ...

Thin films having rock-salt-like structure deposited on amorphous surfaces

US Pat. 6190752 - Filed Nov 12, 1998 - Board of Trustees of the Leland Stanford Junior University

In one example MgO **IBAD** films 16 were deposited on an amorphous Si₃N₄ layer ...

The **flux** ranged from 110-120 //A/cm². The **angle** between the **ion beam** and the ...

Method for preparing high temperature superconductor

US Pat. 6361598 - Filed Jul 20, 2000 - The University of Chicago

Typical **IBAD deposition** rates are about 1.5 A/seconds. ... technique can be used to create a plume of **incident flux** which travels toward a substrate. ...

Superconductor fabrication processes

US Pat. 7338683 - Filed May 10, 2004 - Superpower, Inc.

According to an embodiment, the **IBAD (ion beam assisted deposition)** system ... the **buffer** layer during **deposition** at a oblique 55 **incident angle** from ...

Methods for forming superconducting conductors

US Pat. 6998028 - Filed Sep 24, 2004 - Superpower, Inc.

According to an embodiment, **ion beam assisted deposition** is utilized to ... and the growing **buffer** film) during **deposition**, at a oblique **incident angle** from ...